

SYSTEMS AND METHODS FOR DEPOSITING MATERIAL ONTO
MICROFEATURE WORKPIECES IN REACTION CHAMBERS

ABSTRACT OF THE DISCLOSURE

Systems and methods for depositing material onto a microfeature workpiece in a reaction chamber are disclosed herein. In one embodiment, the system includes a gas supply assembly having a first gas source, a first gas conduit coupled to the first gas source, a first valve assembly, a reaction chamber, and a gas distributor carried by the reaction chamber. The first valve assembly includes first and second valves that are in fluid communication with the first gas conduit. The first and second valves are configured in a parallel arrangement so that the first gas flows through the first valve and/or the second valve. It is emphasized that this Abstract is provided to comply with the rules requiring an abstract. It is submitted with the understanding that it will not be used to interpret or limit the scope or meaning of the claims. 37 C.F.R. § 1.72(b).